Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	4117	(measur\$3 or detect\$3) near9 ((particle or defect) near6 substrate)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:14
L2	937	monomer and particle near3 counter	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:11
L3	3	1 and 2	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:11
L4	136750	(measur\$3 or detect\$3) near9 (particle or defect)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:14
L5	639	2 and 4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:14
L6	18	5 and integrated near2 device	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR.	ON	2005/08/09 11:24
L7	303	5 and (substrate or wafer)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:15
L8	301	5 and (substrate or (semiconductor near device))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:16
L9	100	5 and particle near9 (substrate or (semiconductor near device))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:16
L10	85	9 and particle near size	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:16

L11	9	10 and laser near scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:17
L12	19	10 and laser near scan\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:17
L13	3	5 and particle near6 wafer	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:27
L14	27	2 and particle near6 wafer	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:31
L15	62	2 and laser near2 scan\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:31
L16	28	2 and laser near2 scanner	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:31
L17	28	16 or 16	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/08/09 11:31